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MUETING RAASCH GEBHARDT

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Expedited Examining Procedure
Response -Under 37 C.F.R. §1.116
Group 1765

PATENT
Docket No. 150.00560104

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| | | | | |
|-------------------|---|---|-----------------|---------|
| Applicant(s): | Lee et al. |) | Group Art Unit: | 1765 |
| | |) | | |
| Serial No.: | 10/050,639 |) | Examiner: | Duy Deo |
| Confirmation No.: | 6476 |) | | |
| | |) | | |
| Filed: | January 15, 2002 |) | | |
| | |) | | |
| For: | METHOD AND COMPOSITION FOR SELECTIVELY ETCHING AGAINST COBALT SILICIDE | | | |

RESPONSE UNDER 37 CFR §1.116

Assistant Commissioner for Patents
Mail Stop AF
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The following remarks are provided in response to the Final Office Action mailed
November 4, 2003.

Remarks begin on the page entitled "Remarks."